

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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10/075566
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Applicants: Hidemitsu Aoki, et al.

Examiner: S. T. Chaudhry

Serial No.: ~~unassigned~~ 10/075566

Art Unit: 1746

Filed: ~~herewith~~ 2-13-02

Docket: 12688A

For: METHOD FOR CLEANING
SEMICONDUCTOR WAFER AFTER
CHEMICAL MECHANICAL POLISHING
COPPER WIRING

Dated: February 13, 2002

SAH
#3
S-1-02

Assistant Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In accordance with 37 C.F.R. §§1.97 and 1.98, it is requested that the following references, which are also listed on the attached Form PTO-1449, be made of record in the above-identified case.

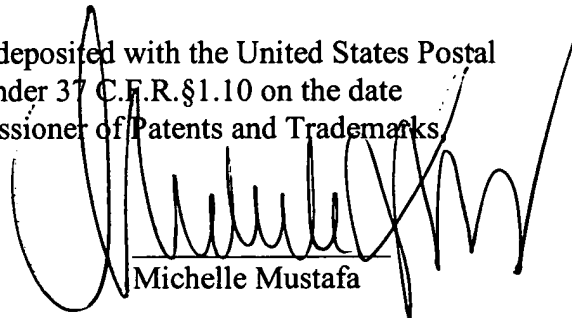
1. "APOST-CMP CLEANING OF W AND SiO₂: A MODEL STUDY", by Igor J. Malik, et al., 1995 Materials Research Society, Soc. Symp. Proc. Vol. 386, pages 109-114,

CERTIFICATE OF MAILING BY EXPRESS MAIL

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I hereby certify that this correspondence is being deposited with the United States Postal Service Express Mail Post Office to Addressee service under 37 C.F.R. §1.10 on the date indicated above and is addressed to the Assistant Commissioner of Patents and Trademarks, Washington, D.C. 20231.

Dated: February 13, 2002


Michelle Mustafa

2. "A Electrochemistry Handbook", 4th edition, pages 276-277.
3. Japanese Unexamined Patent Application Number H9-157692, dated June 17, 1997.
4. Japanese Unexamined Patent Application Number H7-263430, dated October 13, 1995.
5. Japanese Unexamined Patent Application Number H9-100494, dated April 15, 1997.
6. Japanese Unexamined Patent Application Number H6-196461, dated July 15, 1994.
7. Japanese Unexamined Patent Application Number H6-116770, dated April 26, 1994.
8. U.S. Patent No. 5,454,901 to Tsuji dated October 3, 1995.
9. U.S. Patent No. 5,676,760 to Aoki, et al. dated October 14, 1997.
10. U.S. Patent No. 5,762,779 to Shiramizu, et al. dated June 9, 1998.
11. U.S. Patent No. 5,783,790 to Mitsumori, et al. dated July 21, 1998.
12. U.S. Patent No. 5,927,305 to Shiba, dated July 27, 1999.
13. U.S. Patent No. 6,082,373 to Sakuurai, et al. dated July 4, 2000.
14. U.S. Patent No. 6,115,867 to Nakashima, et al. dated September 12, 2000.
15. U.S. Patent No. 6,156,661 to Small, dated December 5, 2000.
16. U.S. Patent No. 6,199,563 to Uehara, et al. March 13, 2001.

Each of the references were made of record in the parent application, U.S. serial number 09/313,027, filed on May 17, 1999, upon which the present application is relying upon for an earlier effective filling date. The items listed on the PT0-1449 form accompanying this Information Disclosure Statement were either cited by the U.S. Patent and Trademark Office or made of record by applicants in an Information Disclosure Statement that was in compliance with 37 C.F.R. §1.98(a)-(c).

Even though some of the art cited may not be in the English language, the concise statement of relevance, pursuant to 37 C.F.R. 1.98(a)(3), relative to these references, was submitted in the Information Disclosure Statements submitted in the parent application, the contents of which are incorporated herein by reference.


Pursuant to 37 C.F.R. §1.98(d), copies of the above-listed references are not provided, as reference numbers 1-7 were previously submitted to the U.S. Patent and Trademark Office with the Information Disclosure Statements filed in the parent application and references 8 through 16 were cited by the Examiner in the parent application. The relevance of reference No. 1 has been described in the specification.

Applicants respectfully request that this Information Disclosure Statement be made of record herein.

Consideration of this Information Disclosure Statement is respectfully requested, since the art provided may be material to the examination of the present application as filed under 37 C.F.R. §1.56.

Inasmuch as this Information Disclosure Statement is being submitted in accordance with the schedule set out in 37 C.F.R. §1.97(b), no statement or fee is required.

Respectfully submitted,



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